	Application No.	Applicant(s)
Notice of Allowability	10/767,047	KOTTER ET AL.
	Examiner	Art Unit
	Anne M. Hines	2879
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to <u>Amendment filed 3/15/07</u> .		
2.  The allowed claim(s) is/are <u>10-12,14-25 and 32-34.</u>		
3.		
Attachment(s)  1. Notice of References Cited (PTO-892)  2. Notice of Draftperson's Patent Drawing Review (PTO-948)  3. Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date  4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	5. ☐ Notice of Informal F 6. ☐ Interview Summary Paper No./Mail Da 7. ☐ Examiner's Amenda 8. ☑ Examiner's Statema 9. ☐ Other	(PTO-413), te

## **DETAILED ACTION**

## Response to Amendment

The amendment filed on March 15, 2007, has been entered and acknowledged by the Examiner.

Claims 10-12, 14-25, and 32-34 are pending in the instant application.

## Allowable Subject Matter

Claims 10-12, 14-25, and 32-34 are allowed.

Regarding independent claim 10, the references of the Prior Art of record fail to teach or suggest the combination of the limitations as set forth in claim 10, and specifically comprising the limitation wherein an apparatus for making a ceramic arc tube comprises a pressure jacket with a pressure chamber and RF susceptor, the susceptor having an opening for receiving the capillary end of an arc tube, an RF induction coil external to the pressure jacket surrounding the RF susceptor, the RF induction coil connected to an RF power source and embedded in a cooling block; the pressure chamber is connected to a source of pressurized buffer gas and a vacuum source, the source of pressurized buffer gas is regulated by a valve and pressure controller, the controller having a pressure sensor for measureing the pressure chamber pressure; a holder for supporting the arc tube, the height of the support selected to cause an unsealed end of the arc tube to be positioned within the RF susceptor when the holder is sealed to the apparatus.

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Regarding claims 11-12, 14-20, and 22-25, claims 11-12, 14-20, and 22-25 are allowable for the reasons given in claim 10 because of their dependency status from claim 10.

Regarding independent claim 21, the references of the Prior Art of record fail to teach or suggest the combination of the limitations as set forth in claim 21, and specifically comprising the limitation wherein an apparatus for making a ceramic arc tube comprises a pressure jacket with a pressure chamber and RF susceptor, the susceptor having an opening for receiving the capillary end of an arc tube, an RF induction coil external to the pressure jacket surrounding the RF susceptor, the RF induction coil connected to an RF power source; the pressure chamber is connected to a source of pressurized buffer gas and a vacuum source, the source of pressurized buffer gas is regulated by a valve and pressure controller, the controller having a pressure sensor for measureing the pressure chamber pressure, the pressure jacket being releasably sealed to a base mounted to a manifold, the manifold having ports for connecting to the source of pressurized buffer gas and the vacuum source, the base and the manifold each having ports for connecting to the source of pressurized buffer gas and the vacuum source, the base and the manifold each having a bore therethrough to allow an arc tube to be inserted into the pressure chamber, the manifold being releasably sealed to a holder for supporting the arc tube, the height of the support selected to cause an unsealed end of the arc tube to be positioned within the RF susceptor when the holder is sealed to the apparatus.

Regarding claims 32-34, claims 32-34 are allowable for the reasons given in claim 10 because of their dependency status from claim 10.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Anne M. Hines whose telephone number is (571) 272-2285. The examiner can normally be reached on Monday through Friday from 8:00-4:30.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nimesh Patel can be reached on (571) 272-2457. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

MARICELI SANTIAGO PRIMARY EXAMINER

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